

In the Claims:

Please amend claims 1-2, and add new claims 8-11 as follows:

1. (Currently Amended) A vacuum processing apparatus comprising a vacuum chamber, at least one vacuum pump, a pipe connecting said vacuum chamber to said vacuum pump for evacuating said vacuum chamber, a flexible pipe included in a part of said pipe, and a mechanism configured for fixing said ~~flexible pipe~~vacuum pump so as not to shrink said flexible pipe at the time of evacuation.

2. (Currently Amended) A vacuum processing apparatus according to claim 1, wherein said mechanism configured for fixing said ~~flexible pipe~~vacuum pump so as not to shrink said flexible pipe at the time of evacuation fixes the vacuum pump side of said flexible pipe.

3. (Original) A vacuum processing apparatus according to claim 1, wherein said mechanism is arranged in a pipe extending from said vacuum pump.

4. (Original) A vacuum processing apparatus according to claim 3, wherein said at least one vacuum pump comprises a plurality of vacuum pumps, said mechanism includes a member fixed to the pipes extending upward from said vacuum

pumps, and said member is a long member extending over said plurality of the vacuum pumps.

5. (Original) A vacuum processing apparatus according to claim 1, wherein said vacuum chamber includes a device for reading an alignment mark of a substrate in the vacuum.

6. (Original) A vacuum processing apparatus according to claim 5, wherein said substrate comprises a substrate of a display device.

7. (Original) A vacuum processing apparatus according to claim 1, wherein said apparatus is a substrate bonding apparatus of a liquid crystal display device.

8. (New) The vacuum processing apparatus as set forth in claim 1, wherein said mechanism includes:

a floor panel on which said vacuum chamber and said vacuum pump are placed; and

a coupling member which connects between said vacuum pump and said floor panel in a direction in which said flexible pipe extends.

9. (New) The vacuum processing apparatus as set forth in claim 8, wherein said coupling member is a chain block.

10. (New) The vacuum processing apparatus as set forth in claim 8, further comprising an inlet pipe included as part of said connecting pipe and extending from said vacuum pump,

said coupling member connecting between said inlet pipe and said floor panel.

11. (New) The vacuum processing apparatus as set forth in claim 8, wherein:

said coupling member connects between a fixing block provided on said floor panel and said vacuum pump; and

said fixing block is provided so that said fixing block and said vacuum chamber sandwich said vacuum pump and face each other.